

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|-------|------|--|---|------------------|---------|------------------|
| L1 | 13 | TOLCHINSKY-P TOLCHINSKY-PETER TOLCHINSKY-PETER-G | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/10/15 12:56 |
| L2 | 1 | (porous near2 silicon) with (substrate wafer) with (support near1 (substrate layer)) with (silicon near1 layer) with (device near1 layer) | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/10/15 12:59 |
| L3 | 0 | (porous near2 silicon) with (substrate wafer) with (support near1 (substrate layer)) with (silicon near1 layer) with (device near1 layer) with (removing splitting) | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/10/15 12:58 |
| L4 | 2 | (porous near2 silicon) same (substrate wafer) same ((support temporary) near1 (substrate layer)) same (silicon near1 layer) same (device near1 layer) | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/10/15 13:01 |
| L5 | 57 | (porous near2 silicon) and (substrate wafer) and ((support temporary) near1 (substrate layer)) and (silicon near1 layer) and (device near1 layer) | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/10/15 14:21 |
| L6 | 59 | (porous near3 silicon) and (substrate wafer) and ((support temporary) near1 (substrate layer)) and (silicon near1 layer) and (device near1 layer) | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/10/15 14:43 |
| L7 | 2 | (porous with silicon) same (substrate wafer) same ((support temporary) near1 (substrate layer)) same ((silicon near1 layer) wafer) same (device near1 layer) | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/10/15 14:45 |